

Notice of References Cited	Application/Control No. 10/673,501	Applicant(s)/Patent Under Reexamination MITROVIC, ANDREJ S.	
	Examiner AKASH SAXENA	Art Unit 2128	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Su-shing Chen, "AEMPES: An expert system for in-situ diagnostics and process monitoring" ; Semiconductor Manufacturing Science Symposium, 1990. ISMSS 1990., IEEE/SEMI International, 21-23 May 1990 Page(s):119 - 122
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